

FIS920000409US1  
I26-0013

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

|             |   |   |                         |
|-------------|---|---|-------------------------|
| Applicant:  | Sievers et al.                                    | ) |                         |
|             |   | ) |                         |
| Serial No.: | 09/887,791  | ) | Group Art Unit: 1765    |
|             |   | ) |                         |
| Filed:      | June 22, 2001                                     | ) | Examiner: Ahmed, Shamim |
|             |   | ) |                         |
| For:        | FOCUSED ION BEAM PROCESS<br>FOR REMOVAL OF COPPER | ) |                         |
|             |   | ) |                         |

## AMENDMENT B

Via Facsimile to: 703-872-9310  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This amendment is submitted in response to the Office Action dated May 21, 2003.  
Please amend the application as follows: